

Abstract:

An electromechanical micromirror device comprises a device substrate with a 1st surface and a 2nd surface, control circuitry disposed on said 1st surface, and a micromirror disposed on said 2nd surface. Arrays of such micromirror devices are also described and may be used as a spatial light modulators (SLMs). The arrays may be 1 dimensional (linear) or 2 dimensional. Methods of fabricating micromirror devices and arrays of such devices are also disclosed. Such methods generally involve providing a device substrate with a 1st surface and a 2nd surface, fabricating control circuitry on the 1st surface, and fabricating micromirror(s) on the 2nd surface.